

# MTCS 2200 - Gas

## Micro Thermal Conductivity Sensor for Gas

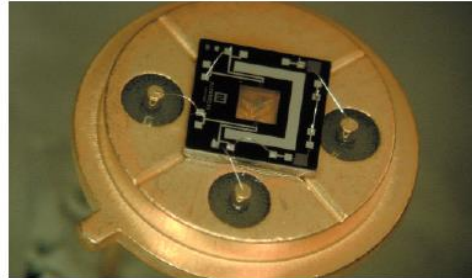
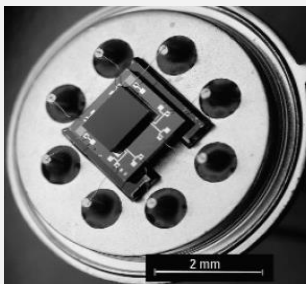
### Applications

#### Industry

- Determining gas concentration by measuring the thermal conductivity in binary mixture (Ar, H<sub>2</sub> in N<sub>2</sub>) or quasi-binary mixture (H<sub>2</sub>, He or CO<sub>2</sub> in air)
- Combustion control
- Monitoring of CH<sub>4</sub> concentration in Natural Gas for gas engine control
- Detection of refrigerant gases such as Freons (R-11; R-12, R-21, R-22), CFC or CF<sub>3</sub>CH<sub>2</sub>F Fluoroethane (R-134 or R-404) for leakage monitoring of cooling systems
- Measurement of Hydrogen (0 to 5% or higher), Helium (0 – 5000 ppm) or Xenon in air
- Security
- Industrial process control, horticulture, food storage, fermentation process control
- Micro vacuum device as miniature Pirani gauge
- Micro absolute humidity sensor in air based on thermal conductivity
- Beverage industry (CO<sub>2</sub> concentration)

#### Domestic use

- CO<sub>2</sub> safety monitoring (0-4%) for Security, Fire Alarms or Indoor Air Quality
- Detection of cooking point in microwave ovens



### General description

The thermal conductivity gas sensor is manufactured on silicon with thin film deposition and silicon micro-machining techniques. This device determines gas concentrations of binary or ternary gas mixtures.

The sensor structure consists of an integrated heater located on a thin electrical and thermal insulating membrane. Two thin film resistors are used for heating and measuring the temperature [T<sub>m</sub>] of the membrane. Two reference resistors are integrated on the silicon beside the membrane area for the compensation of the ambient temperature changes. The four resistors are passivated to protect them from the effects of the gas and are electrically connected to a TO8 or TO5 base by gold wire bonding.

The sensor is attached to a silicon support which also permits gas exchange to the lower side of the membrane. The upper side or the lower side of the membrane is a micro-structure consisting of a cavity anisotropically etched in silicon. The hollow space thus formed between the membrane and the colder part is the gas thermal conductivity measuring section. The measured gas diffuses into the cavity above the heated membrane through the lateral opening, preventing flow perturbation. The thermal heat transfer of the sensor will depend on the thermal conductivity of the gas surrounding the membrane. A constant current circuit is generally used with such sensors for gas measurement. The gas concentration directly depends on the temperature difference [ $\delta T = T_m - T_{amb}$ ] which is measured using the electrical power variation.

**Neroxis has been developed Thermal Conductivity Gas Sensor integrated on silicon**

## Sensor Structure

		Typ.	Min.	Max.	Unit
<b>Insulating membrane</b> • Membrane material: LPCVD silicon nitride • Film thickness: 0.3 µm • Membrane dimensions: 1.0 x 1.0 mm	• Resistances, $R_{m1}$ , $R_{m2}$	120	110	135	Ω
	• Resistances, $R_{t1}$ , $R_{t2}$	270	240	300	Ω
<b>Heater</b> • Heater material: Evaporated nickel • Film thickness: 0.25 µm	• $(R_{t1} + R_{t2}) / (R_{m1} + R_{m2})$	2.24	2.12	2.36	
	• $ R_{m1} - R_{m2} $	< 1.5			Ω
<b>Dimensions of the sensor</b> • Chip dimensions: 3.5 mm x 3.5 mm x 0.76 mm • Including TO8 base: $\varnothing = 13$ mm; h = 15.4 mm • Including TO5 base: $\varnothing = 9.2$ mm; h = 4.6 mm	• $ R_{t1} - R_{t2} $	< 5.5			Ω
	• Temp. coeff. 20-100, $\alpha$	0.0045	0.0050	0.0055	K <sup>-1</sup>

## Structural properties

- Typical heating power: < 6 mW
- Membrane excess temperature: 50 - 70 °C
- Geometry factor, G:  $3.9 \times 10^{-3}$
- Thermal time constant: < 100 ms
- Gas/Humidity response time: < 10 s

## Main advantages

- Silicon micromachined sensor with very small dimensions ( $3.5 \times 3.5$  mm<sup>2</sup>) and for miniature gas volume (20 mm<sup>3</sup>)
- Short time constant (membrane time constant < 5 ms)
- Low power, highly sensitive with a minimal heating power (< 6 mW)
- Independent of flow
- Integrated sensing resistance on membrane as well as temperature compensation resistors
- Reliable and reproducible sensitivity performances
- Small dispersion of the sensor specifications due to batch fabrication processes
- Linear output signal versus target gas concentration
- Very stable long term operation
- High mechanical resistance
- No field maintenance

## Ordering information

### Part number: MTCS 220X – Y - Z

X	Y	Z
1: Binary mixture 2: CH <sub>4</sub> 3: CO <sub>2</sub> 4: H <sub>2</sub> , He 5: CFC, Freon 6: Ar, Ne, N <sub>2</sub> , O <sub>2</sub>	1: TO5-4 2: TO8 3: TO5-(6+2)	1: Aluminium metallization and wire bonding 2: Gold metallization and wire bonding

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